

**FIG.\_1B** 

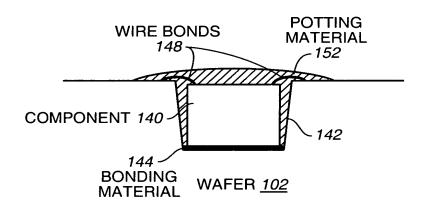
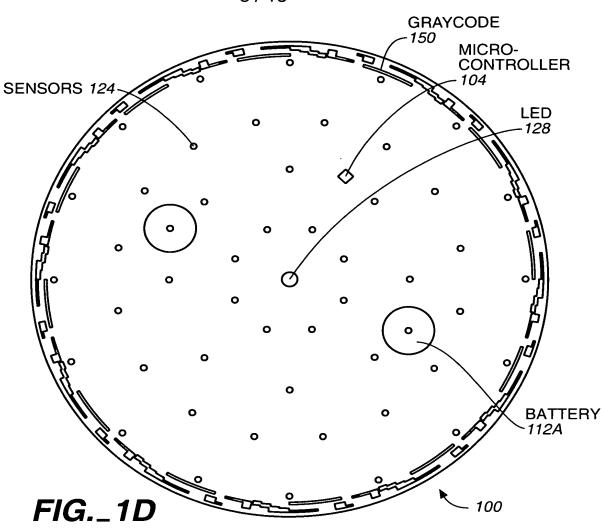
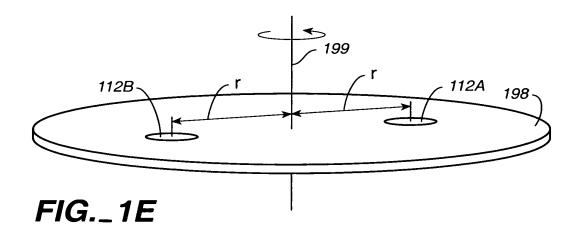


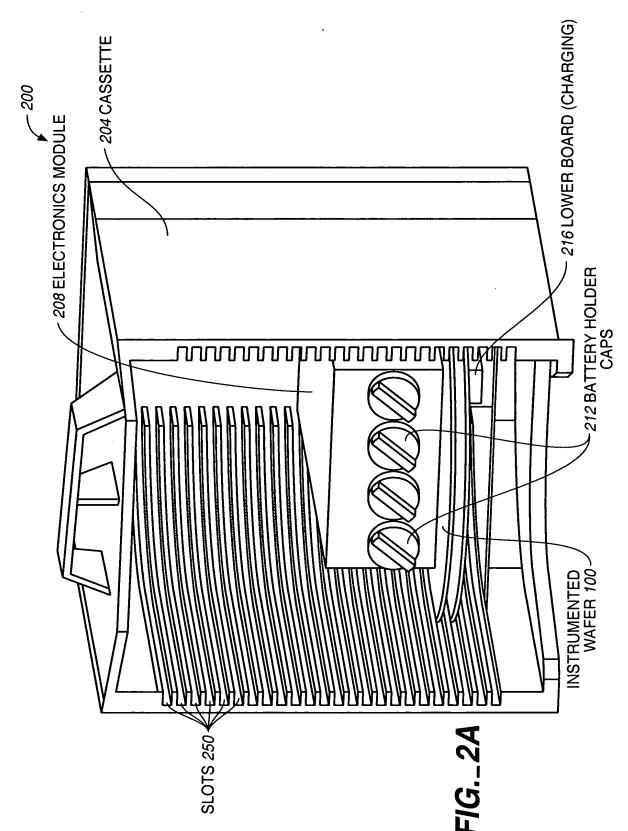
FIG.\_1C

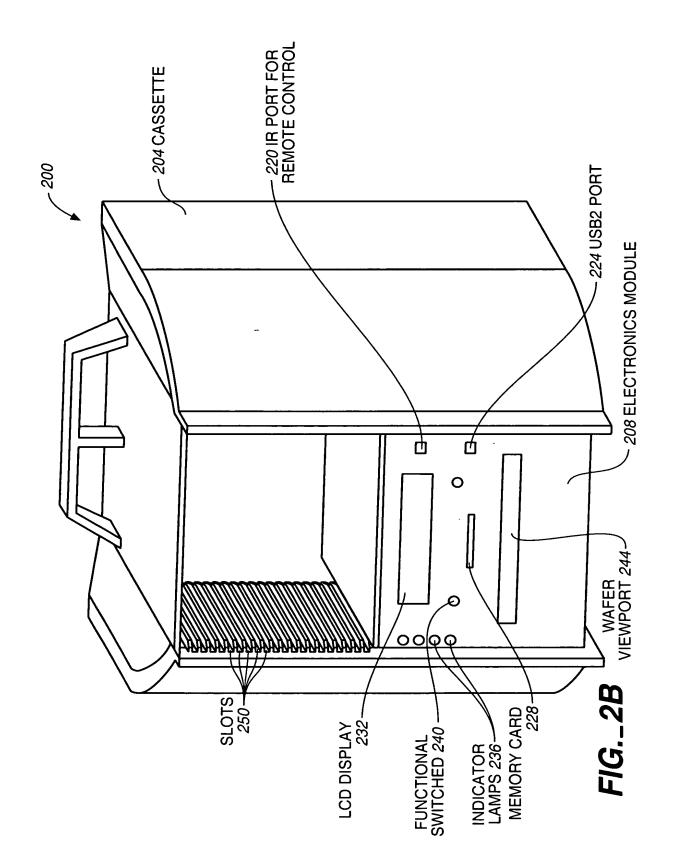












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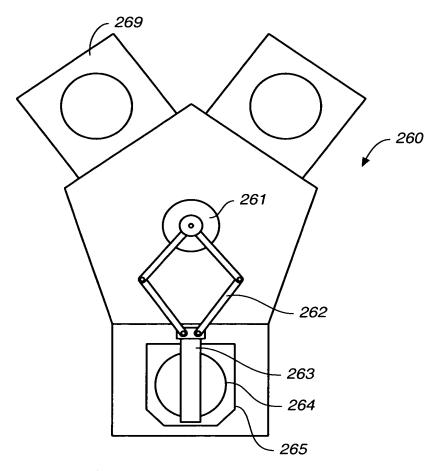


FIG.\_2C

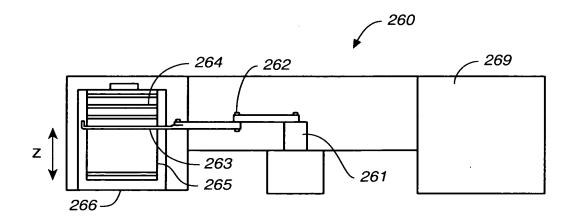
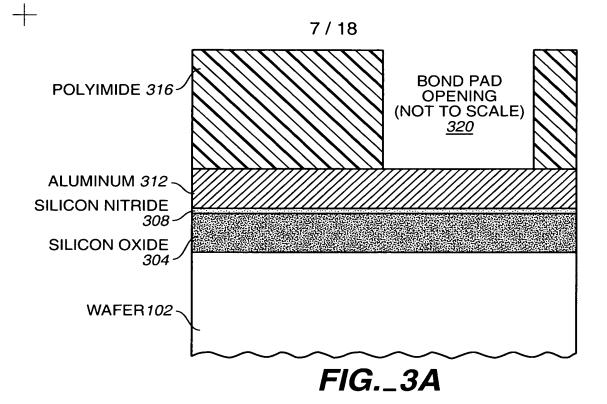
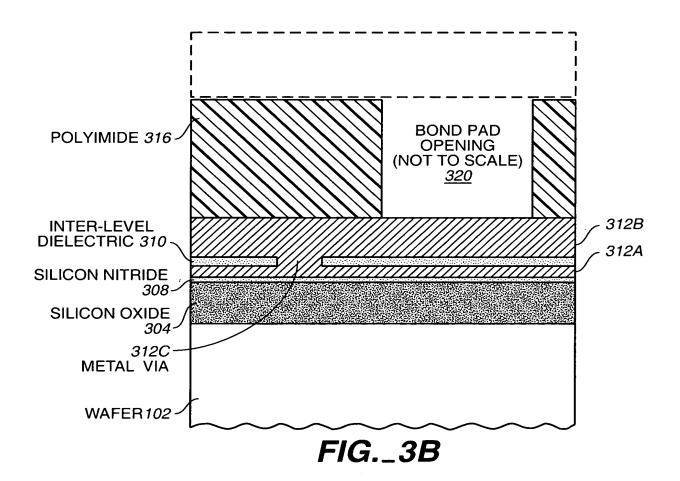


FIG.\_2D





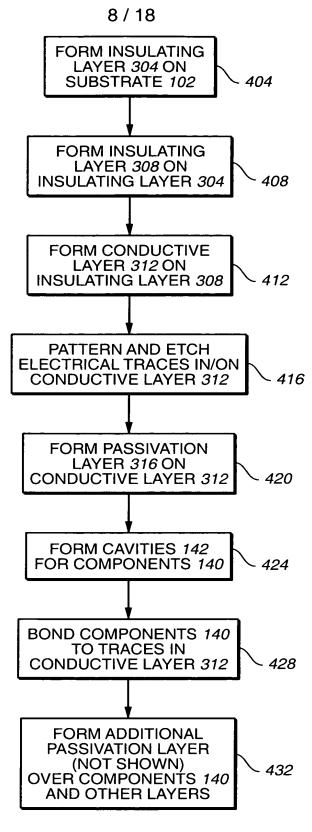


FIG.\_4A

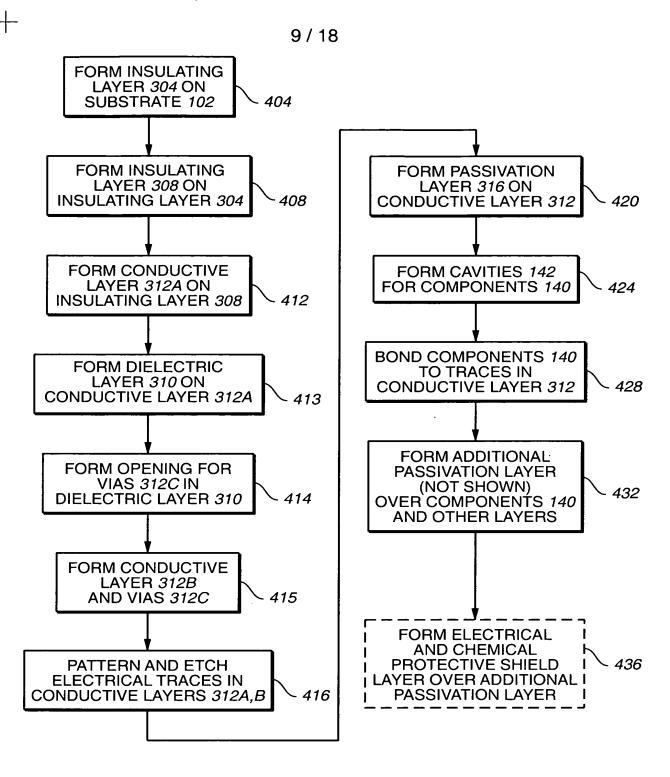
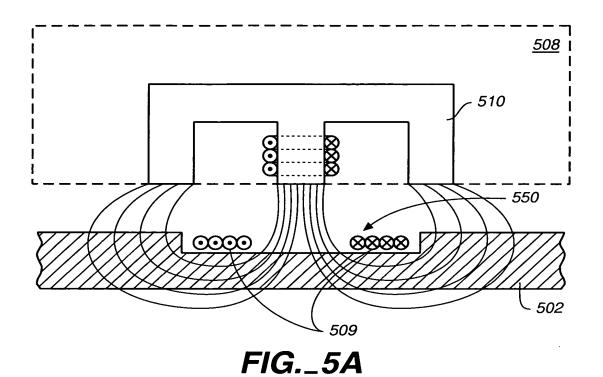
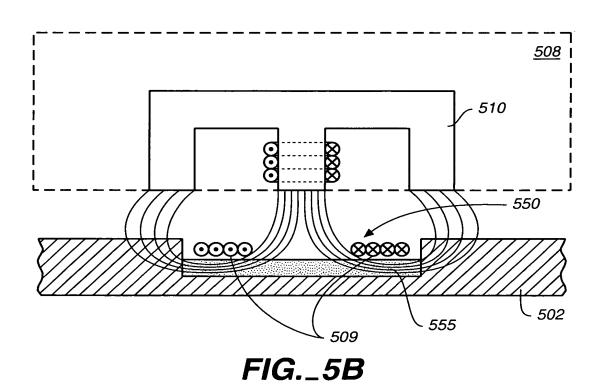
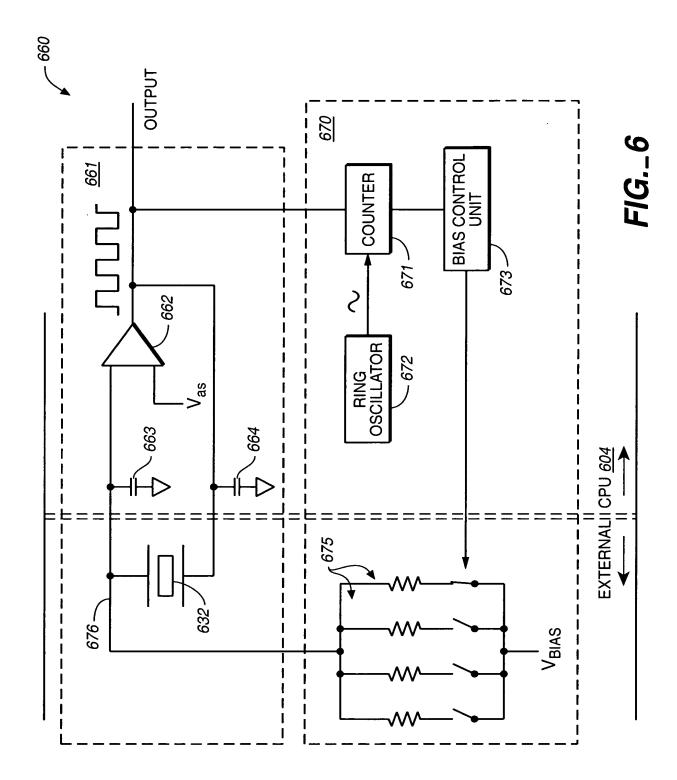


FIG.\_4B

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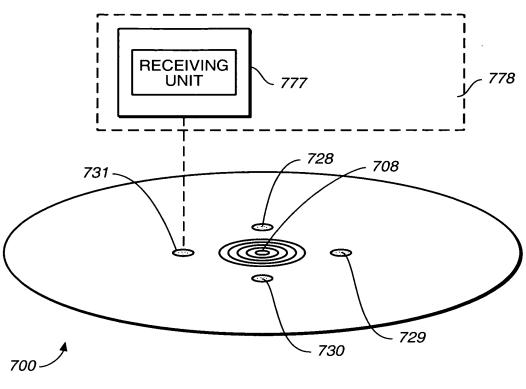


FIG.\_7

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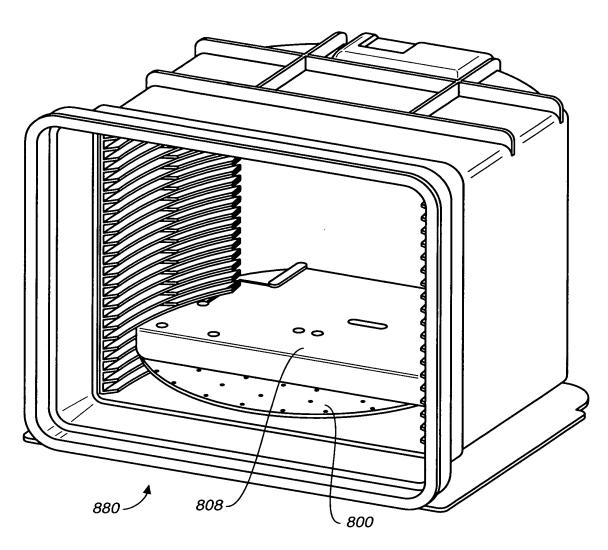


FIG.\_8A

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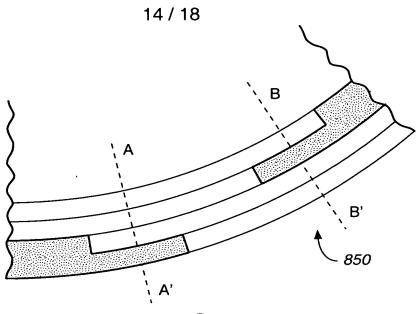
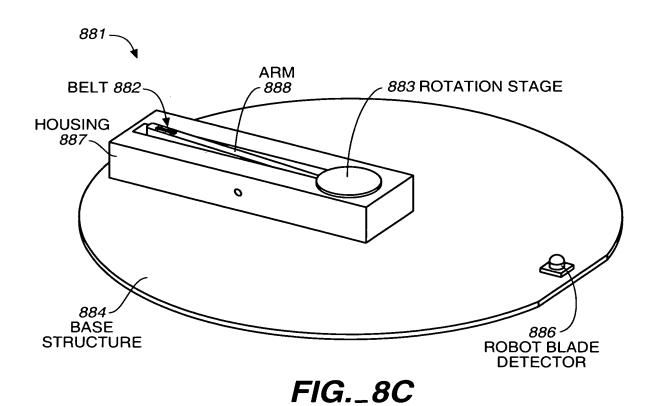


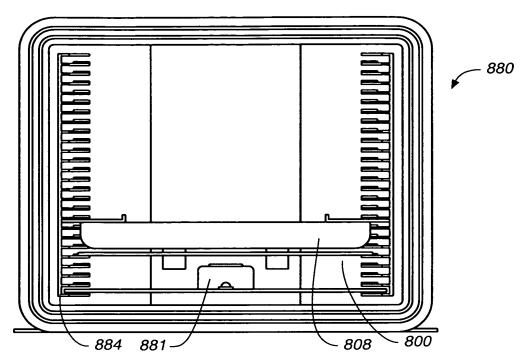
FIG.\_8B



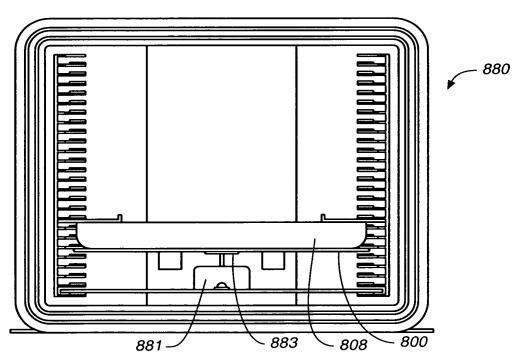
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Appth. No.: 10/718,269 Docket No.: SENS.008US3
Title: Integrated Process Condition Sensing Wafer and Data Analysis System Inventors: Renken et al. Filing Date: November 19, 2003
Atty. Tel: (415) 318-1160 Conf. No.: 9982 Sheet 15 of 18

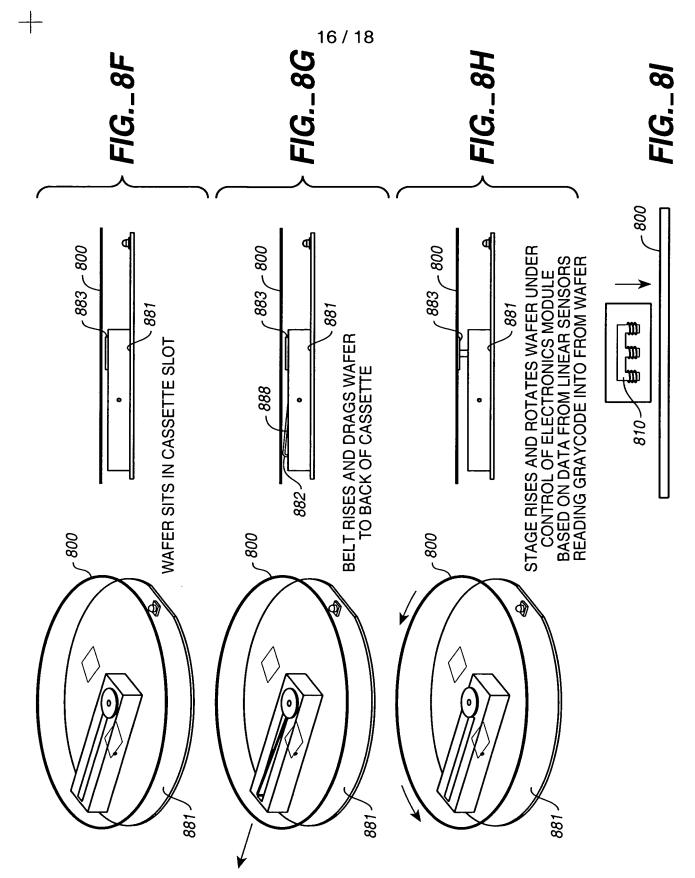
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WAFER IN SLOT READY TO PICK UP **FIG.\_8D** 



wafer raised for rotation alignent and charging  $\pmb{FIG.\_8E}$ 



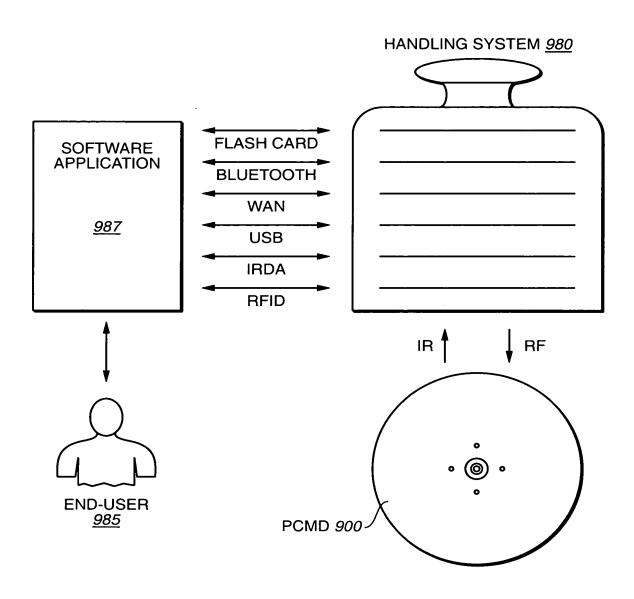
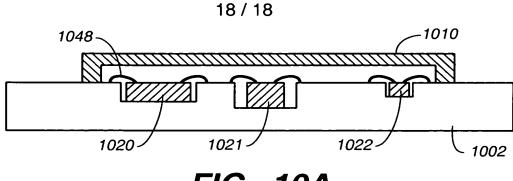


FIG.\_9

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**FIG.\_10A** 

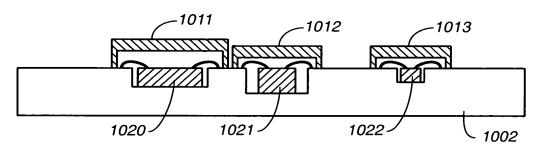


FIG.\_10B

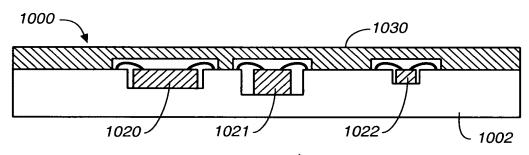


FIG.\_10C

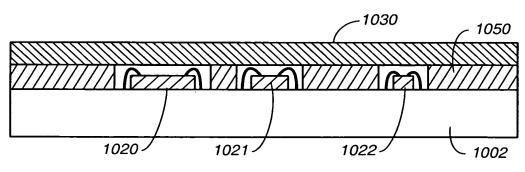


FIG.\_10D